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# Insight into the Oxidation Mechanism of a Cu-Based Oxygen Carrier $(Cu \rightarrow Cu_2O \rightarrow CuO)$ in Chemical Looping Combustion

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ABSTRACT: Cu-based materials have been regarded as suitable oxygen carrier (OC) candidates in chemical looping combustion as a result of their high reactivity. Because Cu is a common reduction product in the fuel reactor and can be reoxidized to CuO in the air reactor, obtaining insights into the complete oxidation process of Cu at a microcosmic level is critical for exploring the intrinsic oxidation mechanism and kinetics. In this work, the detailed oxidation steps have been investigated by density functional theory calculations. First, the most likely dissociative adsorption pathways of oxygen molecules on the Cu(111) surfaces are determined. On the basis of the Mulliken charge analysis and partial density of state analysis, the oxygen uptake process would preferentially produce a CuO nano-island rather than  $Cu_2O$  on the surface. Then, ions  $(O^{2-}$  and  $Cu^{2+})$  diffusion pathways are examined to explore the details of oxide growth. Oxygen inward diffusion leads to the formation of Cu<sub>2</sub>O, however with quite high energy barriers. On the contrary, the horizontal diffusion of copper atoms on the surface is quite easy in kinetics and thermodynamics, corresponding to an epitaxial growth of the CuO oxide nano-island and then the formation of an exterior thin CuO layer. Furthermore, the continuous outward diffusion (replenishing copper atoms for the epitaxial growth) of copper atoms in the Cu or Cu<sub>2</sub>O bulk is also considered. Results show that the energy barrier of each diffusion step in the Cu(111) bulk is smaller than that in the  $Cu_2O(111)$  bulk, indicating that the bulk  $Cu_2O$  phase preferentially forms as a result of copper outward diffusion in the Cu(111) bulk and then is oxidized to generate the bulk CuO phase eventually. In such a way, a complete oxidation mechanism of Cu  $\rightarrow$  Cu<sub>2</sub>O  $\rightarrow$  CuO is elucidated, which has been validated by a well-designed thermogravimetric experiment of controllable oxidation of pure copper.

# 1. INTRODUCTION

Chemical looping combustion (CLC),<sup>1-4</sup> which allows a sequestration-ready CO<sub>2</sub> stream to be directly generated from an innovative two-step reaction, has been raised as a promising carbon capture and storage (CCS) technology. There are two reactors in the chemical looping system, i.e., fuel reactor (FR) and air reactor (AR). It is well-known that the oxygen carrier (OC) is the key in CLC for its role of carrying active lattice oxygen and heat from the AR to the FR. The fuels are oxidized in the FR with the participation of active lattice oxygen of OCs, while at the same time, the OCs with high oxygen potential are reduced to the low-valence oxides or elementary substance. The reduced OCs are then transported to the AR, where they are reoxidized by air and regenerated back to high-valence oxides, liberating a large amount of heat. The regenerated metal oxides are recycled back to the FR for finalizing a loop. More than 700 OC materials have been examined in the literature.<sup>5</sup> Ni-, Fe-, Cu-, Mn-, and Co-based OC materials were widely tested in CLC. $^{6-10}$  As a common OC in CLC, CuO is reduced to Cu in the FR and then regenerates itself via  $Cu \rightarrow Cu_2O \rightarrow CuO$  in the AR, and the copper oxidation process (strong exothermic reaction) usually leads to an undesired sintering/agglomeration of Cu-based OC particles.<sup>11-13</sup> A fundamental understanding of the oxidation features will help to design high-performance and robust Cubased OCs.

Until now, numerous experimental mechanism analyses have been conducted for exploring the oxidation characteristics of

copper.<sup>14–23</sup> In the low-temperature region (350–550 °C), Park et al.<sup>17</sup> found that the surface reaction with the whisker formation on the outside was the dominant mechanism of copper oxidation. Mimura et al.<sup>19</sup> considered that the growth of Cu<sub>2</sub>O predominated the oxidation in an intermediate temperature range (600-800  $^{\circ}$ C), including the lattice diffusion and the grain boundary diffusion, while the lattice diffusion would mainly contribute to the oxidation process at high temperatures (850-1050 °C) for a sharp disappearance of grain boundaries. Zhu et al.<sup>18</sup> reported that pure copper would produce both  $Cu_2O$  and CuO in an oxidation process, and the surface is always covered by a thin layer of cupric oxide before the complete consumption of metallic copper. They conjectured the oxidation mechanism in the further research<sup>2</sup> as follows: at the initial stage of the oxidation, the reaction 2Cu +  $O_2 \rightarrow 2CuO$  on the gas-solid interface happens directly, and the later process is the formation of  $Cu_2O$  on the interface between Cu and CuO. However, these mechanisms are based on the microscopic experimental measurements, which cannot in situ monitor the distribution of oxides and the migration of

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phase boundaries in the bulk. Therefore, an insight into the oxidation process of the Cu-based OC is highly desired.

As a consequence of the reaction mechanism, kinetics is an intuitional description. The previous conclusions of Cu oxidation kinetics are varied.<sup>17–19,25–27</sup> The mathematical models for oxidation rates based on the thickness of oxide as a function of time are always discrepant. Because it is intensively affected by the experimental environment, the length of the oxidation time, and the nature of the initial copper sample (size and single crystal or polycrystalline), it is hard to establish a consensus oxidation kinetic description. On the other side, although it is widely accepted<sup>28</sup> that the oxidation process of Cu<sub>2</sub>O and Cu includes molecular oxygen adsorption, nucleation in the surface, and growth of the oxide, the underlying information is usually missing. Numerous studies $^{29-31}$  have pointed out that the growth of copper oxide is epitaxial across the surface and dominated by the outward diffusion of the cations. The existing works<sup>32-36</sup> mainly paid attention to the chemisorption and surface reconstruction processes at the initial stage of oxidation; however, they were rarely concerned about the O<sub>2</sub>/substrate reaction itself and the details of crystalline island formation. In our recent research,<sup>2</sup> the oxidation mechanism and kinetics of reduction product  $Cu_2O$  in chemical looping with oxygen uncoupling (CLOU) have already been explored. However, it must be noted that there are two stages in the Cu oxidation process  $(2Cu + 0.5O_2)$  $\rightarrow$  Cu<sub>2</sub>O and Cu<sub>2</sub>O + 0.5O<sub>2</sub>  $\rightarrow$  2CuO), and our previous study<sup>27</sup> has merely investigated the second oxidation stage (Cu<sub>2</sub>O + 0.5O<sub>2</sub>  $\rightarrow$  2CuO). The reliable oxidation mechanism of pure Cu is still ambiguous for its polyvalent transition (Cu<sup>0</sup>  $\rightarrow$  Cu<sup>+</sup>  $\rightarrow$  Cu<sup>2+</sup>) in both the superficial layer and the bulk phase at an atomic layer. In this sense, there is an urgent need of more underlying information to clarify the various kinetics and ambiguous understanding of nucleation in copper oxidation.

The behavior of the OC in the AR is intrinsically dependent upon the electron and crystal structures of metal oxides. For example, the oxygen release rate of CuO is relatively stable in a CLOU experiment.<sup>37</sup> This is because the rate-limiting steps for CuO decomposition are the formation and desorption of O<sub>2</sub> according to the density functional theory (DFT) calculations, which are little affected by the conversion ratio. Through a theoretical study, it is found that the improvement of inert supports in sintering resistance is significantly influenced by the bond length and the adsorption energy between CuO and support materials.<sup>38</sup> An atomic modeling by the DFT method will effectively demonstrate the gas-solid reaction in a chemical looping process based on the detailed structure information and the energy profiles of every constituent elementary steps.<sup>39,40</sup> In this study, DFT calculations are used to investigate the Cu oxidation mechanism, including exploring the oxygen uptake pathways, the properties of products at the initial stage of Cu oxidation, and the atomic transport process that reflects the detailed nucleation information. This paper is a follow-up study to explore the oxidation mechanism of pure Cu, which will be beneficial to the holistic comprehension of the intrinsic reaction mechanism and kinetics of many multivalent oxides about the oxidation, sulfidation, and other reactions.

# 2. METHODS

**2.1. DFT Calculations.** In this study, the Cambridge Serial Total Energy Package  $(CASTEP)^{41}$  program package is used for all DFT

calculations, in which the generalized gradient approximation (GGA) in the form of Perdew-Wang (PW91) is chosen for the electron exchange-correlation energy. The interactions of electrons and ions are modeled by the ultrasoft pseudo-potential.<sup>42</sup> The Broyden-Fletcher-Goldfarb-Shanno (BFGS) method is used to search the lowest energy structure, and the cutoff energy is chosen as 400 eV. The Hubbard parameter U is introduced to describe the strong electron correlations of transition metals according to the well-known GGA + U method,  $^{43}$  and 7.5 eV is set as a reasonable U value for the Cu 3d orbitals.<sup>38,44</sup> The van der Waals-inclusive correction (DFT-D) with the Ortmann-Bechstedt-Schmidt (OBS) method is applied for the DFT calculations. The Brillouin zone of the Cu bulk cell and the Cu(111) slabs are sampled with  $8 \times 8 \times 8$  and  $4 \times 4 \times 1$  Monkhorst-Pack k-point meshes, and the Brillouin zone of the Cu<sub>2</sub>O bulk cell and the Cu<sub>2</sub>O(111) slabs are sampled with  $6 \times 6 \times 6$  and  $5 \times 5 \times 1$ Monkhorst-Pack k-point meshes. The convergence criteria for total energy, maximum interatomic force, and displacement are  $1.0 \times 10^{-5}$ eV/atom, 0.03 eV/Å, and 0.001 Å, respectively.

As shown in Figure 1a, the bulk lattice parameters of Cu unit cells  $(a = b = c = 3.606 \text{ Å}, \text{ and } \alpha = \beta = \gamma = 90^\circ)$  are in good agreement with

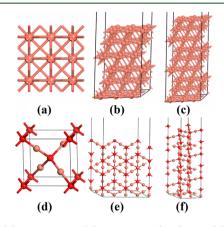


Figure 1. (a) Cu unit cell, (b) six-layer Cu(111) slab, (c) nine-layer Cu(111) slab, (d) Cu<sub>2</sub>O unit cell, (e) six-layer Cu<sub>2</sub>O(111) slab, and (f) nine-layer Cu<sub>2</sub>O(111) slab (salmon pink ball, Cu; red ball, O).

the experimental values (a = b = c = 3.604 Å, and  $\alpha = \beta = \gamma = 90^{\circ}$ ).<sup>45</sup> As shown in Figure 1d, the bulk lattice parameters of Cu<sub>2</sub>O unit cells (a = b = c = 4.279 Å, and 90°) are in good agreement with the experimental values (a = b = c = 4.269 Å, and  $\alpha = \beta = \gamma = 90^{\circ}$ ).<sup>46</sup> Additionally, as for the surface calculations, the six-layer p (3 × 3) Cu(111) (shown in Figure 1b) and p (2 × 1) Cu<sub>2</sub>O(111) (shown in Figure 1b) and p (2 × 1) Cu<sub>2</sub>O(111) (shown in Figure 1c) and p (1 × 1) Cu<sub>2</sub>O(111) slabs (shown in Figure 1f) are applied for the bulk calculations, while the bottom two layers are fixed, and the top seven layers are relaxed. The vacuum space of 15 Å is added perpendicular to the surface, and all three-dimensional (3D) structures are put into periodic boundary conditions. For more details, please refer to our previous work.<sup>27,44</sup>

In this study, the adsorption energy of the  $\rm O_2$  molecule on the surface,  $E_{\rm ads^\prime}$  is defined as

$$E_{ads} = E(O_2/slab) - E(O_2) - E(slab)$$
(1)

where  $E(O_2)$  and E(slab) are the total energies of the free  $O_2$ molecule and the bare slab, respectively, and  $E(O_2/\text{slab})$  presents the total energy of the adsorption structure. The complete linear/ quadratic synchronous transit (LST/QST) approach<sup>47</sup> is used to find out the transition state (TS) as well as the energy barrier  $E_b$ , which is defined as

$$E_{\rm b} = E({\rm TS}) - E({\rm IS}) \tag{2}$$

where E(TS) and E(IS) are the energies of the transition state and the initial state, respectively.

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**2.2. Experimental Approach.** The OC samples used in this study are pure Cu  $\langle 111 \rangle$  crystals (Hefei Kejing Materials Technology Co., China), which are in the shape of a square slice with 5 mm in length and 1 mm in thickness, as shown in Figure 2a. The purity of

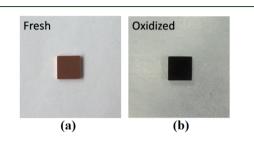
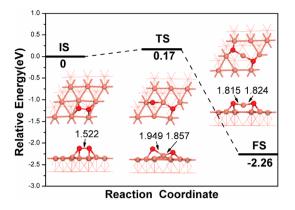


Figure 2. (a) Fresh copper specimens and (b) oxidized copper specimens after the oxidation experiment.

the samples reaches 99.9999%. The isothermal oxidation experiment is carried out in a synchronous thermal analyzer (SETARAM, France) at 600 °C. First the sample is heated to 600 °C with a constant rate of 20 K/min, while N<sub>2</sub> of 50 mL/min is used to sweep the sample. Next, a 20 vol %  $O_2/N_2$  atmosphere is employed as the oxidizing agent for 10 h, and the gas flow rate is controlled at 50 mL/min by a mass flow meter/controller. After copper oxidation, the cross-section of the partially oxidized sample is cleaved within a resin cladding and characterized with scanning electron microscopy (SEM, ZEISS Gemini, Germany). Finally, the microstructure and elemental distribution of the partially oxidized sample (shown in Figure 2b) are characterized by an energy dispersive spectroscopy (EDS, ZEISS Gemini, Germany).

# 3. RESULTS AND ANALYSIS

3.1. Incipient Surface Oxidation of Cu(111): The Formation of the CuO Nano-island on the Surface. First, to find the potential adsorption sites, the oxygen molecule is placed toward the surface. On the Cu(111)surface, there are three kinds of potential adsorption sites [top site (labeled as T), bridge site (labeled as B), and hollow site (labeled as H)] for  $O_2$  adsorption. Both vertical orientation (V) and horizontal orientation (H) are considered in this work. As shown in Figure 3, six structures of O<sub>2</sub> adsorptions are thus considered, while the geometric structure of "HT" means that O<sub>2</sub> horizontally adsorbs at the top site on the surface. After geometry optimization, as shown in Figure 3 (HH), the final stable construction of "HH" ( $O_2$  horizontally adsorbs at the hollow site) shows the largest adsorption energy of -2.30 eV. Therefore, the structure of "HH" is regarded as the most stable adsorption, which has been set as the initial state of the surface oxidation [as shown in Figure 4 (IS)]. The length of the O–O bond is stretched to 1.522 Å (from 1.239 Å in the free molecule state), while the distance between the  $O_2$ 



**Figure 4.** Pathway of  $O_2$  dissociation on the perfect Cu(111) surface, combining the configuration evolution with the energy profile along the reaction coordinate.

molecule and Cu surface is only 1.930 Å. To determine the favorable dissociation pathway of the oxygen molecule, two O atoms are moved along the horizontal direction as the O-O bond is broken and the stable dissociation configuration with the lowest overall energy is chosen as the final state (FS) of the incipient surface oxidation.

As shown in Figure 4, the incipient surface oxidation process of Cu(111) can be summarized as below. Two oxygen atoms are induced to disperse to a closer position on the surface and bond with surrounding copper atoms gradually Figure 4 (IS)]. Along with this process, a copper atom near the adsorption site is drawn away from the compact surface as a result of the attraction of the two oxygen atoms [Figure 4 (TS)], forming a horizontal O-Cu-O structure protruded from the surface [Figure 4 (FS)]. This structure, as a result of stress release in the top of the wetting layer, might induce the formation of the nano-island on the Cu(111) surface and then lead to an epitaxial growth of oxide. The O2 dissociation process is exothermic with a reaction heat of -2.26 eV, and the energy barrier is only 0.17 eV, indicating that this dissociation is energy-favorable in both thermodynamics and kinetics, respectively.

To identify the components of the oxide nano-island, the partial density of states (PDOS) for three valence states of copper cations (Cu, Cu<sup>2+</sup>, and Cu<sup>+</sup>) is depicted in Figure 5. A similar peak appears near the Fermi level in both the oxidized copper cation on the Cu(111) surface [labeled by Cu@ Cu(111), calculated above] and a Cu<sup>2+</sup> cation in a complete CuO(111) surface [Cu@CuO(111), as a reference], and they also share a very similar peak shape around -2 eV, indicating that the electronic orbitals of Cu@Cu(111) are close to those

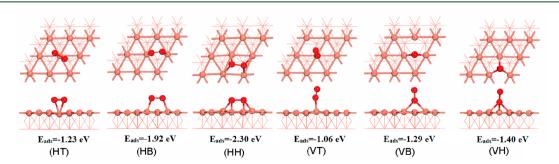


Figure 3. Optimized geometric structures of  $O_2$  adsorption on the Cu(111) surface.

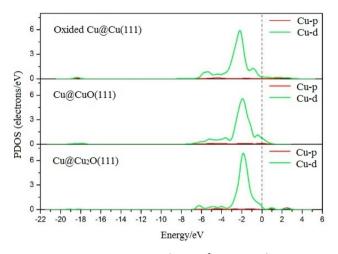


Figure 5. PDOS of Cu atoms (Cu,  $Cu^{2+}$ , and  $Cu^{+}$ ) at different surfaces.

of Cu@CuO(111) rather than Cu@Cu2O(111) (also as a reference). Additionally, an alternative method of identifying phase transformation is the charge analysis.<sup>48</sup> On the basis of the same set of optimization parameters, the Mulliken charges of the Cu cations in both  $Cu_2O(111)$  and CuO(111) bulk models are computed. Calculated results indicate that the Mulliken charge of all of the copper cations in the  $Cu_2O(111)$ bulk ranges from 10.6 to 10.8 e, while that of all of the copper cations in the CuO(111) model ranges from 10.2 to 10.5 e. Therefore, the involved copper cation charge of the nanoisland is then analyzed [as given by Figure 4 (FS)]. The copper cation bonding with the two oxygen anions possesses a total Mulliken charge of 10.42 e, which means that Cu<sup>0</sup> has been first oxidized to Cu<sup>2+</sup> rather than Cu<sup>+</sup>. Therefore, it can be concluded that, at the very initial stage, the surface oxidation of Cu(111) will first form a CuO nano-island above the surface, while the main component in the bulk is still Cu phase, which also partially validates the hypothesis of Zhu et al.<sup>24</sup>

**3.2.** Subsequent Surface Oxidation of Cu(111): The Formation of an Exterior Thin CuO Layer. After the incipient surface oxidation, a CuO nano-island with high oxygen potential and relatively low copper concentration is formed, which would motivate the growth of the oxide island and then the formation of a thin CuO layer during the further exposure to  $O_2$ . There are two potential processes for this evolution. One is the inward diffusion of the surface oxygen atom, and the other is the outward diffusion of the sublayer copper atom. Thus, the final state [Figure 4 (FS)] of the incipient surface oxidation is set as the initial state of both oxygen anion and copper cation diffusions.

At first, the energy profile of oxygen inward diffusion is shown in Figure 6a. The oxygen atom (marked by blue) is moved from the surface to the next layer with an energy barrier of 1.90 eV to break the bonds between this oxygen atom and the surface copper atoms. The reaction energy of this process is 1.78 eV, indicating that plenty of heat is required for the oxygen inward diffusion. It can be observed in Figure 6 (FS) that the migrated oxygen atom bonds with the sublayer copper atoms and then turns to be a four-coordinated structure, which is similar to the standard tetrahedral site residing in the  $Cu_2O(111)$  lattice (shown in Figure 6b), indicating the formation of subsurface  $Cu_2O$ . Meanwhile, the Mulliken charge of the copper adatom increases from 10.42 to 10.64

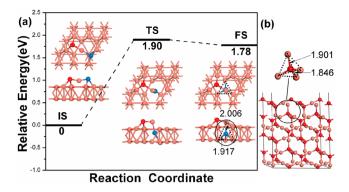
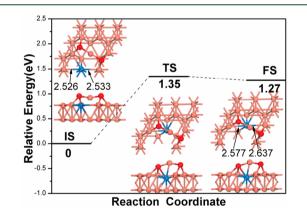


Figure 6. (a) Structures and energy profile of IS, TS, and FS for oxygen inward diffusion in the Cu(111) slab (the diffused O atom is marked blue) and (b) structure of the Cu<sub>2</sub>O slab and its tetrahedral site.

e, which also signifies a transformation from  $Cu^0$  to  $Cu^+$ . Thus, this oxygen inward diffusion process would be a possible mechanism for the initial formation of the  $Cu_2O$  phase in the surface.

Furthermore, an investigation about the external diffusion of sublayer copper to the nano-island is carried out as well. The nearest sublayer copper atom (Cu<sub>sub</sub>) under the surface copper vacancy (V<sub>Cu</sub>) is first considered; however, after geometry optimization, it is found that Cu<sub>sub</sub> would prefer to move back to the original site instead of entering the surface layer. This means that the movement of Cu<sub>sub</sub> to V<sub>Cu</sub> is rather difficult. Meanwhile, it must be noted that, during a real oxidation process, the high temperature intensifies the vibrations of all atoms and the copper atoms on the same layer around V<sub>Cu</sub> would also migrate along different orientations. As shown in Figure 7, a neighbor sublayer copper atom (the blue ball)



**Figure 7.** Structures and energy profile of IS, TS, and FS for copper surface diffusion in the Cu(111) slab (the diffused Cu atom is marked blue).

tends to move horizontally to  $V_{Cu}$  and little change to the surface copper concentration and less bond cleavage facilitate this surface migration. As a result, the CuO nano-island is lifted farther away from the substrate [Figure 7 (FS)], completely echoing the epitaxial growth mechanism.  $^{29-31}$ 

As seen, the epitaxial growth of the nano-island might mainly be produced by the copper surface diffusion rather than the outward diffusion. Meanwhile, the energy barrier and reaction heat of this horizontal diffusion are 1.35 and 1.27 eV, respectively, and apparently, both of them are lower than those

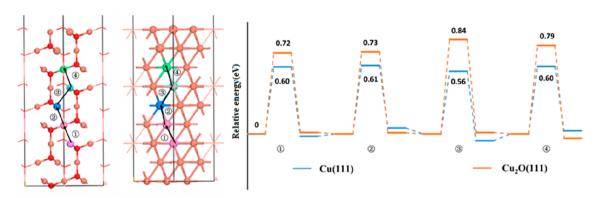


Figure 8. Cu diffusion paths and energy profile with energy barriers in the Cu(111) and  $Cu_2O(111)$  bulk (the colorized balls present the diffusion Cu cations).

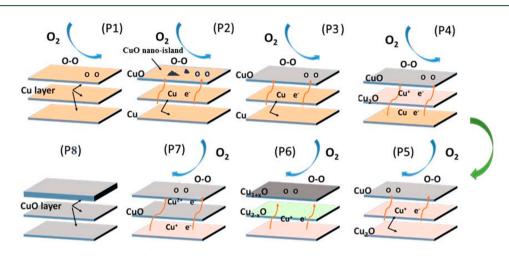


Figure 9. Schematic of the oxidation process of  $Cu \rightarrow Cu_2O \rightarrow CuO$ .

of oxygen inward diffusion (1.90 and 1.78 eV). Thus, it can be concluded that the copper horizontal diffusion (correspondingly, the CuO nano-island growth) is easier than the oxygen inward diffusion (correspondingly, the sublayer Cu<sub>2</sub>O growth). That is, as a result of this subsequent surface oxidation, the growth of the CuO nano-island will lead to the formation of an exterior thin CuO layer above the surface of the Cu(111) bulk as more nano-islands are produced and then grow rather than Cu<sub>2</sub>O.

3.3. Bulk Oxidation of Cu(111): The Successive Formation of Cu<sub>2</sub>O and CuO in Bulk. The oxide growth during the high-temperature oxidation process requires a continual source of ions.<sup>49</sup> Above DFT calculations indicate that the onset of oxide formation displays a volume expansion (the epitaxial growth of the oxide nano-island), indicating that the "growth source" should be the copper diffusion in the bulk region.<sup>27</sup> As labeled in Figure 8, the outward diffusions of copper atoms from the deep bulk region to upper layer in the nine-layer Cu(111) and  $Cu_2O(111)$  slab models are calculated, respectively, and four-step diffusions are considered to adequately describe the diffusion pathways. It is found that the energy barriers for the copper diffusion in the bulk region are close to each other, and the diffusion energies are around 0.6 eV in the Cu(111) bulk, while the diffusion energies are about 0.8 eV in the  $Cu_2O(111)$  bulk. The energy barrier of each diffusion step in the Cu(111) bulk is also smaller than that in the  $Cu_2O(111)$  bulk, indicating that oxidation (accompanying with the copper outward diffusion) of the

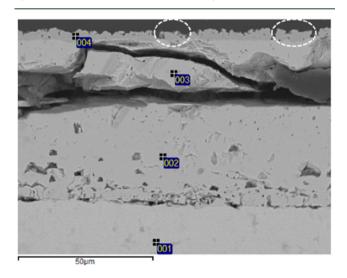
Cu(111) bulk is faster than that of  $Cu_2O(111)$ . It is therefore conjectured that copper oxidation in the Cu(111) bulk (correspondingly, the formation of the Cu<sub>2</sub>O phase) precedes that in the  $Cu_2O(111)$  bulk (correspondingly, the formation of the CuO phase), and Cu<sub>2</sub>O will become the main component in the bulk as metallic copper atoms are entirely consumed. The deduction is also consistent with the thermogravimetric experimental results,<sup>50</sup> in which the oxidation rate of copper would suddenly drop as Cu<sup>0</sup> is converted to Cu<sup>+</sup>. Namely, the main component in the bulk changes in the form of Cu  $\rightarrow$  $Cu_2O \rightarrow CuO$ , while the shell of the bulk would still be the CuO phase. In terms of energy barriers of the whole oxidation process, it can be noted that the energy barrier of the subsequent surface oxidation (1.35 eV) is higher than that of the incipient surface oxidation (0.17 eV) and the bulk oxidation (0.60 eV), indicating that the rate-determined step of the whole oxidation process is the horizontal diffusion of copper atoms on the surface.

**3.4. Copper Oxidation Mechanism.** The complete Cu oxidation process can be divided into two parts, the surface oxidation and the bulk oxidation, which has already been obtained by the above DFT calculations. Thus, the Cu oxidation mechanism can be summarized briefly: (1) At the initial stage, as shown in Figure 9 (P1), the copper atoms on the gas-solid interface react with  $O_2$  rapidly with a small thermodynamic resistance, producing the CuO nano-islands [Figure 9 (P2)]. (2) As a result of the surface horizontal diffusion of the copper atoms, the CuO nano-island gradually

grows, echoing the epitaxial growth of the oxide. An outmost thin CuO layer will be eventually formed on the surface of the Cu(111) bulk as more CuO nano-islands are produced and then grow [as depicted in Figure 9 (P3)]. (3) Next, the sublayer copper atoms will accumulate to the surface to balance the copper concentration gradient between the surface and sublayer. The reaction  $Cu + Cu^{2+} + e^- + h^+ \rightarrow 2Cu^+$ brings a Cu<sub>2</sub>O layer between the surface CuO layer and interior Cu layer. Along with the surface oxygen uptake reaction, as shown in Figure 9 (P4), the Cu<sub>2</sub>O layer grows thicker and more Cu<sup>0</sup> atoms donate electrons, transforming to be  $Cu^+$ . (4) When a complete consumption of the metallic copper happens, as shown in Figure 9 (P5), the  $Cu_2O$  phase becomes the main component of the OC, while the shell would still be the CuO phase. Hence, the first step of the copper oxidation mechanism of  $Cu \rightarrow Cu_2O$  has been obtained.

In combination with our previous research<sup>27</sup> on the Cu<sub>2</sub>O oxidation (Cu<sub>2</sub>O  $\rightarrow$  CuO), a complete oxidation mechanism of Cu is then obtained. (5) As shown in Figure 9 (P6), the slightly excessive copper cations within the external Cu<sub>1+x</sub>O layer continue to react with O<sub>2</sub> molecules quickly, forming a new product layer at the exterior. (6) With the progress of the copper atom outward diffusion, the Cu/O ratio of the "interior layer" approaches 1:1 via Cu<sub>2</sub>O + V<sub>Cu</sub>  $\rightarrow$  CuO, which leads to the formation of CuO in the bulk phase. As presented in Figure 9 (P7), the external CuO layer becomes thicker and thicker. (7) Finally, with the complete conversion of internal Cu<sub>2</sub>O, as shown in Figure 9 (P8), the complete oxidation process of Cu  $\rightarrow$  Cu<sub>2</sub>O  $\rightarrow$  CuO is finished.

**3.5.** Partial Oxidation Experiment of Pure Copper. To validate the first-step oxidation mechanism of Cu, an isothermal oxidation experiment is performed and the partially oxidized sample can be seen in Figure 2b. As shown in Figure 10, the cross section of the partially oxidized sample is characterized by SEM with a 1000 $\times$  magnification level. Naturally, it is noted that the microstructure of the partially oxidized sample consists of three layers: the outer thin layer (points 003 and 004), the middle layer (point 002), and the inner layer (point 001), while the outer surface is also covered by abundant oxide islands (marked by the white dotted line



**Figure 10.** Microstructure of the oxide in copper oxidation at the initial stage (the crannies may result from the different thermal stress in different regions during the temperature-varying period).

frame). The appearance of the nano-islands is in accordance with the simulation results.

Then, these layers are characterized by EDS analysis. In Figure 10 (point 004), there are 20.63 wt % O and 79.37% wt % Cu, which means that the ratio of Cu and O atoms is close to 1:1. That is to say, the outer thin layer must be CuO, which verifies that the oxygen uptake process on the Cu(111) surface would directly produce CuO rather than Cu<sub>2</sub>O. Similarly, it is measured that the middle layer (point 002) is  $Cu_2O$  (11.97 wt % O and 88.03 wt % Cu). At the same time, the inner layer (point 001) remains copper substrate, while the layer (point 003) is a transition region with the Cu/O molar ratio of 1.68:1. As mentioned above, the oxidation of the Cu surface preferentially produces a layer of CuO at first [Figure 9 (P1) and (P2) and Figure 10 (point 4)] and the growth of Cu<sub>2</sub>O is the dominant process in the early stage [Figure 9 (P4) and (P5) and Figure 10 (point 2)]. Consequently, the first-step oxidation mechanism of Cu has been supported by the partial oxidation experiment.

# 4. CONCLUSION

DFT calculations have been employed to investigate the Cu oxidation mechanism in the CLC process. The whole oxidation process can be divided into two steps: the surface oxidation and the bulk oxidation. First, the most likely oxidation pathways for the six-layer Cu(111) surface are obtained. The interface reaction between OC and air is significantly exothermic [4.56 eV for Cu(111)], and the incipient surface oxidation of Cu(111) would preferentially produce a CuO nano-island but not Cu<sub>2</sub>O, which is verified by the Mulliken charge and PDOS analysis of the oxide nano-island. Second, the growth of the oxide nano-island on the surface is then considered. Results indicate that oxygen inward diffusion will lead to the formation of a Cu<sub>2</sub>O-liked structure and copper diffusion prefers a horizontal path, corresponding to an epitaxial growth of the nano-island and then the formation of an exterior thin CuO layer. On the basis of the energy barrier analyses, it is concluded that the growth of the nanoisland (forming a thin CuO layer) is easier than the oxygen inward diffusion (producing a  $Cu_2O$  phase) on the Cu(111)surface with respect to the surface oxidation of Cu. Third, the continuous replenishment process of copper atoms in unreacted bulk is calculated. Results show that the oxidation of the Cu(111) bulk (leading to the formation of the  $Cu_2O$ phase) is faster than that of the  $Cu_2O(111)$  bulk (leading to the CuO formation), and as a result, Cu<sub>2</sub>O will preferentially become the main component in the bulk because metallic copper is entirely consumed. The Cu<sub>2</sub>O bulk is oxidized to form the CuO phase eventually. On the basis of these understandings, a complete oxidation mechanism is established and validated by a well-designed partial oxidation experiment.

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# Notes

The authors declare no competing financial interest.

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